

EAST - [029521c:1]

File View Edit Tools Window Help

Drafts

Pending

Active

- L1: (109557) data near20(region\$3 or local)
- L2: (96623) data near10(region\$3 or local)
- L3: (579) inspect\$4 same parameter same(wafer or semiconductor)
- L4: (145) 12 and 13
- L5: (1047) recip\$3 near9 parameter
- L6: (31) 14 and 15
- L7: (26) 16 and mask
- L8: (2) 16 and (mask near5 data)**

Failed

Saved

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DBs: USPAT, US-PC Plurals

Default operator: OR Highlight all hit terms initially

16 and (mask near5 data)

	U	I	Document ID	Title	Cur
1	<input type="checkbox"/>	<input type="checkbox"/>	US 20030076989	Automated repetitive array microstructure defect inspection	382
2	<input type="checkbox"/>	<input type="checkbox"/>	US 6128403 A	Wafer map analysis aid system, wafer map analyzing method and wafer p	382

Hits Details HTML

Ready

NUM